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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
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10/517,063

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Yoichi Mori

2004-1936A

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WENDEROTH, LIND & PONACK, L.L.P.
2033 K STREET N. W.
SUITE 800
WASHINGTON, DC 20006-1021

EXAMINER

NGUYEN, NGOC YEN M

ART UNIT

PAPER NUMBER

1793

MAIL DATE

DELIVERY MODE

09/24/2008

PAPER

Please find below and/or attached an Office communication concerning this application or proceeding.

The time period for reply, if any, is set in the attached communication.

Office Action Summary	Application No. 10/517,063	Applicant(s) MORI ET AL.	
	Examiner Ngoc-Yen M. Nguyen	Art Unit 1793	

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --

Period for Reply

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) OR THIRTY (30) DAYS, WHICHEVER IS LONGER, FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

Status

- 1) ☐ Responsive to communication(s) filed on 18 July 2008.
- 2a) ☐ This action is **FINAL**. 2b) ☒ This action is non-final.
- 3) ☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

Disposition of Claims

- 4) ☒ Claim(s) 1-14 is/are pending in the application.
- 4a) Of the above claim(s) 9-14 is/are withdrawn from consideration.
- 5) ☐ Claim(s) _____ is/are allowed.
- 6) ☒ Claim(s) 1-8 is/are rejected.
- 7) ☐ Claim(s) _____ is/are objected to.
- 8) ☐ Claim(s) _____ are subject to restriction and/or election requirement.

Application Papers

- 9) ☐ The specification is objected to by the Examiner.
- 10) ☐ The drawing(s) filed on _____ is/are: a) ☐ accepted or b) ☐ objected to by the Examiner.
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).
- 11) ☐ The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.

Priority under 35 U.S.C. § 119

- 12) ☒ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
- a) ☐ All b) ☐ Some * c) ☐ None of:
1. ☐ Certified copies of the priority documents have been received.
 2. ☐ Certified copies of the priority documents have been received in Application No. _____.
 3. ☒ Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).

* See the attached detailed Office action for a list of the certified copies not received.

Attachment(s)

- | | |
|--|---|
| 1) <input checked="" type="checkbox"/> Notice of References Cited (PTO-892) | 4) <input type="checkbox"/> Interview Summary (PTO-413) |
| 2) <input type="checkbox"/> Notice of Draftsperson's Patent Drawing Review (PTO-948) | Paper No(s)/Mail Date. _____ |
| 3) <input checked="" type="checkbox"/> Information Disclosure Statement(s) (PTO/SB/08) | 5) <input type="checkbox"/> Notice of Informal Patent Application |
| Paper No(s)/Mail Date <u>12/3/04 and 6/14/07</u> . | 6) <input type="checkbox"/> Other: _____ |

DETAILED ACTION

Applicant's election without traverse of Group I, claims 1-8 in the reply filed on July 18, 2008 is acknowledged.

Claims 9-14 are withdrawn from further consideration pursuant to 37 CFR 1.142(b), as being drawn to a nonelected invention, there being no allowable generic or linking claim. Applicant timely traversed the restriction (election) requirement in the reply filed on July 18, 2008.

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

Claims 1-8 are rejected under 35 U.S.C. 103(a) as being unpatentable over EP 1101524 in view of Arno (6,905,663).

EP '524 discloses a process for treating a waste gas containing fluorine containing compound (note title). As shown in Figure 1, a waste gas 9 containing PFCs, oxidizing gases, acidic gases and CO is first passed through a spray column 1 so as to remove solids and Si compounds. The waste gas is then passed through the thermal decomposition device 3, which is also supplied with H₂, O₂ and H₂O to decompose the PFCs, oxidizing gases and CO into acidic gases and CO₂. The acidic gases are removed by passage through a subsequent spray column 5, from which

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treated gas 10 emerges (note paragraph [0023] and the Figure). The thermal decomposition device contains an gamma-alumina packed layer as the catalyst (note paragraph [0022]).

EP '524 further teaches that as for PFC, H_2 or H_2O is added in moles at least equal to the moles necessary for F atom in the PFC to be converted into HF (note paragraph [0018]).

The difference is EP '524 does not disclose the step of adding water or hydrogen to the waste gas after heating the waste gas in the presence of oxygen.

Arno '663 discloses a process for the abatement of semiconductor manufacturing effluents containing fluorine gas (note title).

Arno '663 teaches that thermal approaches combine reactive materials and F_2 inside a reactor that is heated using fuel or electrical energy. Existing thermal units require the addition of hydrogen source/fuels such as methane or hydrogen to drive the fluorine reaction to completion, converting fluorine to HF. The by-products generated by the thermal abatement of F_2 typically include hot acids that in turn require the use of a post-treatment water scrubber. The containment of hot concentration acids requires expensive materials of construction to prevent temperature enhanced corrosive attack on lines, vessels and fittings (note column 2, lines 43-58).

In order to overcome the above mentioned deficiencies, Arno '663 discloses a process for abating gaseous fluorocompounds by injecting a fluorocompound abatement medium into the fluorocompound-containing gas, wherein the fluorocompound abatement medium comprises at least one of steam (i.e. water),

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methane and hydrogen, optionally in further combination with a catalyst effective to enhance the abatement, with the proviso that when the fluorocompound abatement medium contains methane and/or hydrogen, the injection of the fluorocompound abatement medium is conducted under non-combustion conditions (note column 3, lines 23-33). As shown in Figures 1-2, the system used consists a gas preheating stage 6, in which the fluorine-containing gas 12 is flowed into the gas flow passage 24 bounded by passage wall 22 in aluminum block 14. The aluminum block 14 is formed in two half-sections 16 and 18. Each of the half sections has respective channels therein that upon mating the other half sections forms a first throughbore for passage of a water line 26 there through, and a second throughbore for installation of a cartridge heater 20 therein. The preheat stage 6 includes an extended length flow path through which the gas stream flows to the reaction stage 7 of the apparatus, while the water line 26 carries water from a suitable source for heating by the cartridge heater 20 to generate steam. The generated steam then is introduced to the gas flow passage 24 at steam entrance 30, at an intermediate section of passage. The steam then mixes and reacts with the fluorine constituents of the gas stream. The heat of the reaction is dissipated by heat exchange cooling coils 32 in cooling section 8 (note column 4, lines 28-63).

As shown in Arno '663, the reaction only take place in the intermediate section, i.e. reaction stage 7, thus, the HF is only formed in reaction stage 7 which can be immediately cooled down in section 8. The need for using expensive materials for construction for handling hot concentrated acid can be avoided.

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It would have been obvious to one of ordinary skill in the art at the time the invention was made to inject the water or hydrogen in the process of EP '524 into the waste gas after such waste gas has been preheated, as suggested by Arno '663, because by doing so, at least the preheat section does not require to be constructed with expensive materials that can handle hot acid.

The prior art made of record and not relied upon is considered pertinent to applicant's disclosure.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Ngoc-Yen M. Nguyen whose telephone number is (571) 272-1356. The examiner can normally be reached on Part time schedule.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Stanley Silverman can be reached on (571) 272-1358. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

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Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

/Ngoc-Yen M. Nguyen/
Primary Examiner, Art Unit 1793

nmn
September 25, 2008